

PATENT APPLICATION

RESPONSE UNDER 37 CFR §1.116 EXPEDITED PROCEDURE TECHNOLOGY CENTER ART UNIT 1763

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kazuo ICHIKAWA et al.

CVD SUBSTRATE AND CLEANING METHOD

Application No.: 09/670,877

Filed: September 27, 2000

Group Art Unit: 1763

Examiner:

R. Zervigon

RECEIVED FEB 19 2004

Docket No.:

107469

AMENDMENT UNDER 37 C.F.R. §1.116

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

For:

In reply to the October 7, 2003 Office Action, the period for reply effectively extended to February 9, 2004 by a Petition for Extension of Time filed herewith, please consider the following:

Amendments to the Claims as reflected in the listing of claims;

Remarks.